



PATENT
Attorney Docket No.: SLM-06400

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

David T. Amm, *et al.*

Serial No.: 09/930,838

Filed: August 15, 2001

For: **BLAZED GRATING LIGHT
VALVE**

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313

) Group Art Unit: 2872

) Examiner: John Juba Jr.

) **INFORMATION DISCLOSURE
STATEMENT**

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Sir:

The citations listed below, copies attached, may be material to the examination of the above-identified application, and are therefore submitted in compliance with the duty of disclosure defined in 37 C.F.R. §§ 1.56 and 1.97. The Examiner is requested to make these citations of official record in this application.

United States Patents or Published Patent Applications have been filed electronically (EFS ID # 43633); (EFS ID #43634); (EFS ID #43635); (EFS ID #43637); (EFS ID #43638); (EFS ID #43639); (EFS ID #43640); (EFS ID #43641); (EFS ID #43643); (EFS ID #43644); (EFS ID #43645); (EFS ID #43648); (EFS ID #43649); (EFS ID #43650); (EFS ID #43652); and (EFS ID #43653).

Applicants have become aware of the following printed publication which may be material to the examination of this application:

- U.S. Patent No. Des. 334,557;
- U.S. Patent No. Des. 334,742;
- U.S. Patent No. Des. 337,320;
- U.S. Patent No. Re. 16,767;
- U.S. Patent No. Re. 25,169;
- German Publication No. DE 32 33 195 A1;
- German Publication No. DE 43 23 799 A1;
- German Publication No. DE 197 23 618 A1;
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- German Publication No. DE 198 46 532 C1;
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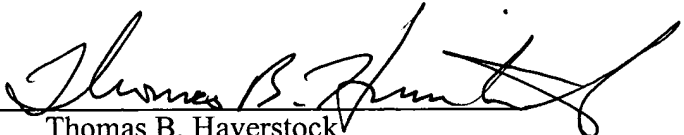
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This Information Disclosure Statement under 37 C.F.R. §§ 1.56 and 1.97 is not to be construed as a representation that a search has been made, that additional information material to the examination of this application does not exist, or that anyone or more of these citations constitutes prior art.

Respectfully submitted,
HAVERSTOCK & OWENS LLP

Dated: 7-15-03

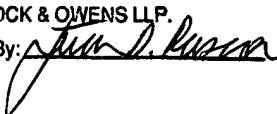
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PATENT
Attorney Docket No.: SLM-06400

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Serial No.: 09/930,838

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For: **BLAZED GRATING LIGHT
VALVE**

) Group Art Unit: 2872

) Examiner: John Juba Jr.

) **TRANSMITTAL LETTER**

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Respectfully submitted,
HAVERSTOCK & OWENS LLP

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Applicants: David T. Amm et al

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| | AD | Re. 16,767 | Jenkins | | | 10/31/22 |
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Examiner:

Date Considered:

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INFORMATION DISCLOSURE STATEMENT BY APPLICANT

Applicants: David T. Amm et al

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Group Art Unit: 2872

FOREIGN PATENTS OR PUBLISHED FOREIGN PATENT APPLICATIONS

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